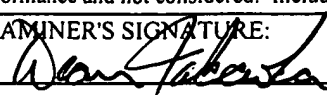


Form PTO-1449				Attorney Docket No. 62020-1450		Serial No. 10/669,178	
INFORMATION DISCLOSURE CITATION				Applicant Ayazi, et al.			
(Use several sheets if necessary)				Filing Date September 23, 2003		Group 2817	
U.S. PATENT DOCUMENTS							
Examiner Initials	Item	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	A	6,549,099	4-15-03	Taussig	333	186	6-29-01
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		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	B	WO 02/01717 A1	1/3/02	PCT			Abstract
	C	WO 03/043189 A2		PCT			Abstract
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	D	Galayko, D., Kaiser, A., Buchailot, L. et al. (2003) Microelectromechanical Variable-Bandwidth IF Frequency Filters With Tunable Electrostatic Coupling Spring. IEEE., pp. 153-156					
	E	No, S.Y., Hashimura, A., Pourkamali, S. et al., Single-Crystal Silicon HARPSS Capacitive Resonators with Submicron Gap-Spacing, School of Electrical and Computer Engineering, Georgia Institute of Technology, GA; for proceedings at Hilton Head 2002.					
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<p>* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.</p>							
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References A - E and G - K are duplicates of the IDS dated 3/12/04 which has been previously considered.